

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Original) An inkjet printhead comprising:
a plurality of nozzles,
a plurality of liquid passages leading to each nozzle respectively for
providing ejectable liquid to the associated nozzle; and,
droplet ejection actuators and associated drive circuitry corresponding to each
nozzle respectively, the nozzles, ejection actuators, associated drive circuitry
and liquid passage being formed on and through a wafer using
lithographically masked etching techniques; wherein,
the wafer has a drop ejection side and a liquid supply side; such that,
each of the liquid passages is formed by etching a hole in the wafer from the
drop ejection side, and etching a supply passage through the wafer from the
liquid supply side of the wafer to form a fluid connection with the hole.
2. (Original) An inkjet printhead according to claim 1 wherein the width of the hole is
greater than 8 microns.
3. (Original) An inkjet printhead according to claim 1 wherein the width of the hole is
less than 24 microns.
4. (Original) An inkjet printhead according to claim 1 wherein the width of the supply
passage is greater than 14 microns.
5. (Original) An inkjet printhead according to claim 1 wherein the width of the supply
passage is less than 28 microns.
6. (Original) An inkjet printhead according to claim 1 wherein the droplet ejection
actuators are thermal bend actuators.
7. (Original) An inkjet printhead according to claim 1 wherein the droplet ejection
actuators are gas bubble generating heater elements.
8. (Original) An inkjet printhead according to claim 7 further including a plurality of
nozzle chambers, each nozzle chamber corresponding to a respective nozzle;
wherein,
at least one the of the gas bubble generating heater elements are disposed in
each of the nozzle chambers respectively; such that,

a bubble forming liquid can be supplied to the nozzle chamber for thermal contact with at least one of the bubble generating heater elements so that a bubble of the bubble forming liquid generated by one of the heater elements causes a droplet of the ejectable liquid to be ejected from the nozzle.

9. (Original) An inkjet printhead according to claim 8 wherein the bubble forming liquid is the same as the ejected liquid.
10. (Original) An inkjet printhead according to claim 1 wherein the printhead is a pagewidth printhead.
11. (Original) A method of ejecting drops of an ejectable liquid from an inkjet printhead, the printhead comprising a plurality of nozzles, a plurality of liquid passages leading to each nozzle respectively;

drop ejection actuators and associated drive circuitry corresponding to each nozzle respectively;

the nozzles, ejection actuators, associated drive circuitry and liquid passage being formed on and through a wafer from lithographically masked etching techniques, such that the wafer has a droplet ejection side and a liquid supply side, and, each of the liquid passages is formed by etching a hole partially through the wafer from the droplet ejection side, subsequently filling the hole with resist then etching a passage from the liquid supply side of the wafer to the resist before stripping the resist from the hole, the method of ejecting drops comprising the steps of:

providing the ejectable liquid to each of the nozzles using the associated liquid passage; and

actuating the droplet ejection actuator to eject droplets of the ejectable liquid from the nozzle.
12. (Original) A method according to claim 11 wherein the width of the hole is greater than 8 microns.
13. (Original) A method according to claim 11 wherein the width of the hole is less than 24 microns.
14. (Original) A method according to claim 11 wherein the width of the supply passage is greater than 14 microns.
15. (Original) A method according to claim 11 wherein the width of the supply passage is less than 28 microns.

